

Supplementary Information

Solution-Processed Nickel Oxide Passivation on Large-Area Silicon Electrodes for Efficient Photoelectrochemical Water Splitting

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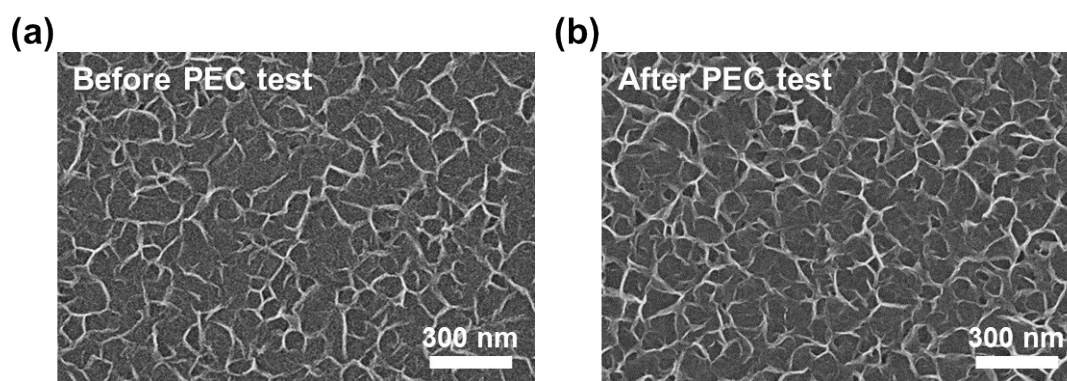


Figure S1. SEM images of NiO nanostructures on n-Si substrates (CBD for 3 min, thermal annealing at 300 °C) (a) before and (b) after PEC measurements.